

## Refine Search

### Search Results -

Terms	Documents
L3 and radii and axes	2

16/829,681 /  
Database:

US Pre-Grant Publication Full-Text Database  
US Patents Full-Text Database  
US OCR Full-Text Database  
EPO Abstracts Database  
JPO Abstracts Database  
Derwent World Patents Index  
IBM Technical Disclosure Bulletins

Search:

L4	<input type="button" value="Refine Search"/>
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### Search History

DATE: Thursday, September 30, 2004 [Printable Copy](#) [Create Case](#)

Set Name Query  
side by side

Hit Count Set Name  
result set

DB=USPT; PLUR=YES; OP=ADJ

<u>L4</u>	L3 and radii and axes	2	<u>L4</u>
<u>L3</u>	L2 and (ignots or legs)	7	<u>L3</u>
<u>L2</u>	L1 and (support adj fixture)	8	<u>L2</u>
<u>L1</u>	monocrystalline and (virgin adj polysilicon)	10	<u>L1</u>

END OF SEARCH HISTORY

## Hit List

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<a href="#">Generate OACS</a>				

Search Results - Record(s) 1 through 2 of 2 returned.

1. Document ID: US 6455395 B1

L4: Entry 1 of 2

File: USPT

Sep 24, 2002

US-PAT-NO: 6455395

DOCUMENT-IDENTIFIER: US 6455395 B1

TITLE: Method of fabricating silicon structures including fixtures for supporting wafers

<a href="#">Full</a>	<a href="#">Title</a>	<a href="#">Citation</a>	<a href="#">Front</a>	<a href="#">Review</a>	<a href="#">Classification</a>	<a href="#">Date</a>	<a href="#">Reference</a>	<a href="#">Claims</a>	<a href="#">KMC</a>	<a href="#">Drawn D</a>
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2. Document ID: US 6450346 B1

L4: Entry 2 of 2

File: USPT

Sep 17, 2002

US-PAT-NO: 6450346

DOCUMENT-IDENTIFIER: US 6450346 B1

TITLE: Silicon fixtures for supporting wafers during thermal processing

<a href="#">Full</a>	<a href="#">Title</a>	<a href="#">Citation</a>	<a href="#">Front</a>	<a href="#">Review</a>	<a href="#">Classification</a>	<a href="#">Date</a>	<a href="#">Reference</a>	<a href="#">Claims</a>	<a href="#">KMC</a>	<a href="#">Drawn D</a>
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<a href="#">Clear</a>	<a href="#">Generate Collection</a>	<a href="#">Print</a>	<a href="#">Fwd Refs</a>	<a href="#">Bkwd Refs</a>	<a href="#">Generate OACS</a>
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Terms	Documents
L3 and radii and axes	2

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### Search Results - Record(s) 1 through 7 of 7 returned.

#### 1. Document ID: US 6727191 B2

L3: Entry 1 of 7

File: USPT

Apr 27, 2004

US-PAT-NO: 6727191

DOCUMENT-IDENTIFIER: US 6727191 B2

TITLE: High temperature hydrogen anneal of silicon wafers supported on a silicon fixture

          

#### 2. Document ID: US 6617225 B2

L3: Entry 2 of 7

File: USPT

Sep 9, 2003

US-PAT-NO: 6617225

DOCUMENT-IDENTIFIER: US 6617225 B2

TITLE: Method of machining silicon

          

#### 3. Document ID: US 6583377 B2

L3: Entry 3 of 7

File: USPT

Jun 24, 2003

US-PAT-NO: 6583377

DOCUMENT-IDENTIFIER: US 6583377 B2

TITLE: Welded silicon member

          

#### 4. Document ID: US 6455395 B1

L3: Entry 4 of 7

File: USPT

Sep 24, 2002

US-PAT-NO: 6455395

DOCUMENT-IDENTIFIER: US 6455395 B1

TITLE: Method of fabricating silicon structures including fixtures for supporting wafers

[Full](#) | [Title](#) | [Citation](#) | [Front](#) | [Review](#) | [Classification](#) | [Date](#) | [Reference](#) | [Claims](#) | [KUMC](#) | [Drawn Ds](#)

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5. Document ID: US 6450346 B1

L3: Entry 5 of 7

File: USPT

Sep 17, 2002

US-PAT-NO: 6450346

DOCUMENT-IDENTIFIER: US 6450346 B1

TITLE: Silicon fixtures for supporting wafers during thermal processing

[Full](#) | [Title](#) | [Citation](#) | [Front](#) | [Review](#) | [Classification](#) | [Date](#) | [Reference](#) | [Claims](#) | [KUMC](#) | [Drawn Ds](#)

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6. Document ID: US 6403914 B1

L3: Entry 6 of 7

File: USPT

Jun 11, 2002

US-PAT-NO: 6403914

DOCUMENT-IDENTIFIER: US 6403914 B1

TITLE: Method for welding silicon workpieces

[Full](#) | [Title](#) | [Citation](#) | [Front](#) | [Review](#) | [Classification](#) | [Date](#) | [Reference](#) | [Claims](#) | [KUMC](#) | [Drawn Ds](#)

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7. Document ID: US 6284997 B1

L3: Entry 7 of 7

File: USPT

Sep 4, 2001

US-PAT-NO: 6284997

DOCUMENT-IDENTIFIER: US 6284997 B1

TITLE: Crack free welding of silicon

[Full](#) | [Title](#) | [Citation](#) | [Front](#) | [Review](#) | [Classification](#) | [Date](#) | [Reference](#) | [Claims](#) | [KUMC](#) | [Drawn Ds](#)

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Terms	Documents
L2 and (ignots or legs)	7

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